

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of Shen et al.	Group Art Unit 1746
Serial No: 09/507,629	Examiner: Allan W. Olsen
Filed: February 18, 2000	Attorney Docket No: 001945 USA P03/SILICON/JB
Title: SELF-CLEANING PROCESS FOR ETCHING SILICON-CONTAINING MATERIAL	July 23, 2002 San Francisco, California

AMENDMENT

Box Fee Amendment  
Commissioner for Patents  
Washington, D C 20231

Examiner Olsen

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March 29, 2002, and is being filed within four months thereof with a request for one month extension of time.

hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

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by WILLIAM J. C. [illegible]      Date: 10/1/81

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